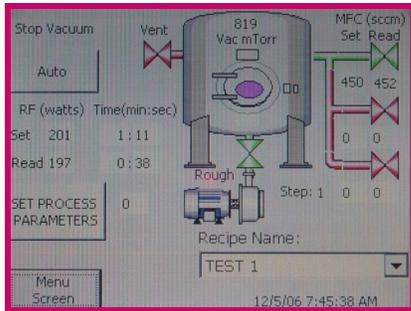


SCE-115 Plasma System



**Siemens S7-200 Series "Touch Panel" Control
Graphic Operational Display - Pass Word Protected**

Inductive Coupling
Ensures multi-directional cleaning or surface modification unmatched by box type systems.



**Inductively Coupled Plasma
ICP**

Optional:
Quartz Rails and Quartz Rack

"Ultra Clean" Quartz Chamber
There are no metal parts inside this chamber, your parts aren't exposed to the particulates associated with metal chambers.

Immersing parts in low temperature plasma may be your final cleaning solution !!
Anatech's plasma systems are CFC and effluent free, operator and environmentally safe, easily operated.

SCE-115 Barrel Plasma System

Control System:

Siemens S7-200
Programmable Logic Controller LCD Display:

Pressure display
Gas flow with mass flow controllers (2)
Single gas input
Process time remaining

Power Requirements:

115 VAC 15A 50/60 HZ

Options:

220 VAC

Control System:

Options:

3rd Gas channel
Data logging
Capacitance manometer
Temperature sensor
Throttle valve
Nitrogen backfill
Slow pump and particle reduction
Operational Light Array

Dimensions:

System comes in a standard 19 inch half rack
36 inch high x 23 inch wide x 27 inch deep
250 lbs Crated weight (estimated)

Vacuum System:

23 CFM Standard
Main Vacuum Valve system controlled
6 feet of 1.500 " ID Vacuum line
Oxygen Service, Class "B" Preparation

Reactor Chamber:

Quartz chamber 15" Diameter x 18" Long
Front Loading
Viewport on front door with UV shield

Options:

Quartz rails & shelves (up to 3)
Quartz Wafer Boats
Planar electrode

Vacuum System:

Options:

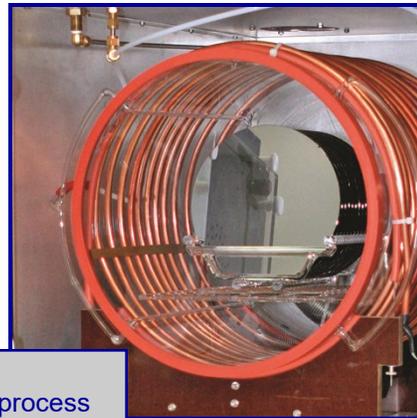
Corrosive service
Mist eliminator
Oil filtration

RF Power Source:

0-1000 Watt, 13.56 MHz
Forward and reflected power reading
Automatic Matching Network

Options:

600 Watt 13.56 MHz supply



Optional:
Quartz Wafer Boat for batch process

CALL ANATECH USA TO DISCUSS YOUR APPLICATION

**Anatech USA
1395 Greg Street Suite 110
Sparks, NV 89431
775-657-8685**